

L Number	Hits	Search Text	DB	Time stamp
1	2799	250/341.8,306,307,559.3.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/22 15:11
2	87	"critical dimension" AND 250/341.8,306,307,559.3.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/22 15:12
3	93	(ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4 nanometrology) AND 250/341.8,306,307,559.3.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/22 15:12
-	0	scatterometry AND 250/237R.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/08/26 16:35
-	205	scatterometry	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/08/26 16:40
-	963	profilometry	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/08/26 16:40
-	0	250/237R.ccls. AND profilometry	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/08/26 16:42
-	8	(scatterometry OR profilometry) AND 356/614,616,620.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 13:27
-	8	(scatterometry OR profilometry OR reflectometry) AND 356/614,616,620.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 14:09
-	4106	(ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension)	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/07 11:28
-	1	((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension)) AND 250/237R.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 14:11
-	331	250/\$.ccls. AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension))	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 14:11
-	224	(wafer substrate (integrated ADJ circuit)) AND (250/\$.ccls. AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension)))	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 14:12
-	142	((wafer substrate (integrated ADJ circuit)) AND (250/\$.ccls. AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension)))) AND @pd<20020225	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 15:33
-	714	((determin\$5 measur\$4) NEAR4 (period pitch dimension)) AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension))	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 15:32
-	219	356/\$.ccls. AND (((determin\$5 measur\$4) NEAR4 (period pitch dimension)) AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension)))	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 15:33

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-	131	(356/\$.ccls. AND (((determin\$5 measur\$4) NEAR4 (period pitch dimension)) AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4) AND (pitch OR dimension)))) AND @pd<20020225	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/09/03 15:33
-	672	356/614,616,620.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/07 11:28
-	1144	250/237R.ccls.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/07 11:28
-	1	("6433878").PN.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/07 14:23
-	9	("4870289" "5164790" "5413884" "5576829" "5879844" "5962173" "5963329" "6137570" "6187483").PN.	USPAT	2003/10/07 14:23
-	17	(ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4 nanometrology) AND (356/614,616,620.ccls. 250/237R.ccls.)	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/22 15:12
-	8	((feature OR structure) WITH (dimension OR measurement OR pitch)) AND ((ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4 nanometrology) AND (356/614,616,620.ccls. 250/237R.ccls.))	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/09 17:15
-	1	("6433878").PN.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/14 15:02
-	1735	(356/399,495,503,625,634,635,630,640).CCLS.	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/20 17:39
-	161	(ellipsomet\$4 reflectomet\$4 profilomet\$4 scatteromet\$4 nanometrology) AND ((356/399,495,503,625,634,635,630,640).CCLS.)	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/20 17:40
-	9	("5867276" "5877880" "5880838" "6051348" "6081334" "6141107" "6245584" "6383888" "6423977").PN.	USPAT	2003/10/21 13:00
-	11107	"integrated circuit" AND pitch AND pattern	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/21 15:13
-	43	scatterometry AND ("integrated circuit" AND pitch AND pattern)	USPAT; US-PGPUB; EPO; JPO; IBM_TDB	2003/10/22 15:10